

Handwritten: *John*  
Docket No.: 50090-334

# 71 BEX  
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Handwritten: *AP 3700*  
PATENT

re Application of

Masanobu IWASAKI, et al.

Serial No.: 09/934,474 ✓

Filed: August 23, 2001

Group Art Unit: 3723

Examiner: H. Shakeri

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING  
POLISHING SOLUTION, APPARATUS FOR AND METHOD OF POLISHING  
SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING  
SEMICONDUCTOR DEVICE

AMENDMENT UNDER 37 CFR §1.116

Handwritten: *all to enter  
w/ appeal*  
Commissioner for Patents  
Washington, DC 20231

Sir:

The following Amendment and Remarks are submitted in response to the Office  
Action dated April 18, 2002, pursuant to the provisions of 37 C.F.R. §1.116.

IN THE CLAIMS:

Please amend claims 3, 5 and 10 as follows.

3. (Twice Amended) The apparatus according to claim 1, wherein each of  
said supply units comprises:

a tank for storing liquid;

a pipe for supplying said liquid from said tank to said mixing unit;